

Contents

| | | |
|----------|---|-------------|
| | Acknowledgements | <i>xv</i> |
| | Nomenclature | <i>xvii</i> |
| | Introduction | <i>1</i> |
| | <i>Oleg B. Malyshev</i> | |
| | References | <i>3</i> |
| 1 | Vacuum Requirements | 5 |
| | <i>Oleg B. Malyshev</i> | |
| 1.1 | Definition of Vacuum | 5 |
| 1.2 | Vacuum Specification for Particle Accelerators | 6 |
| 1.2.1 | Why Particle Accelerators Need Vacuum? | 6 |
| 1.2.2 | Problems Associated with Beam–Gas Interaction | 8 |
| 1.2.2.1 | Beam Particle Loss | 8 |
| 1.2.2.2 | Background Noise in Detectors | 8 |
| 1.2.2.3 | Residual Gas Ionisation and Related Problems | 9 |
| 1.2.2.4 | Contamination of Sensitive Surfaces | 9 |
| 1.2.2.5 | Safety and Radiation Damage of Instruments | 10 |
| 1.2.3 | Vacuum Specifications | 11 |
| 1.2.4 | How Vacuum Chamber Affects the Beam Properties | 12 |
| 1.3 | First Considerations Before Starting Vacuum System Design | 13 |
| 1.3.1 | What Is the Task? | 13 |
| 1.3.2 | Beam Lattice | 14 |
| 1.3.3 | Beam Aperture and Vacuum Chamber Cross Section | 15 |
| 1.3.3.1 | Required Mechanical Aperture | 15 |
| 1.3.3.2 | Magnet Design | 17 |
| 1.3.3.3 | Mechanical Engineering | 17 |
| 1.3.3.4 | Other Factors Limiting a Maximum Size of Beam Vacuum Chamber | 17 |
| 1.3.4 | Vacuum Chamber Cross Sections and Preliminary Mechanical Layout | 18 |
| 1.3.5 | Possible Pumping Layouts | 19 |
| 1.4 | First and Very Rough Estimations | 20 |
| 1.5 | First Run of an Accurate Vacuum Modelling | 22 |
| 1.6 | Towards the Final Design | 22 |

| | | |
|----------|--|-----------|
| 1.7 | Final Remarks | 25 |
| | References | 25 |
| 2 | Synchrotron Radiation in Particle Accelerators | 29 |
| | <i>Olivier Marcouillé</i> | |
| 2.1 | Emission of a Charged Particle in a Magnetic Field | 29 |
| 2.1.1 | Radiated Energy Density and Power Density | 31 |
| 2.1.2 | Angular Flux | 32 |
| 2.2 | SR from Dipoles | 32 |
| 2.2.1 | Emission Duration and Critical Energy | 33 |
| 2.2.2 | Photon Flux | 34 |
| 2.2.3 | Vertical Angular Distribution of Photon Flux | 37 |
| 2.2.4 | Photon Power | 39 |
| 2.2.5 | Vertical Angular Distribution of Power | 41 |
| 2.3 | SR from Quadrupoles | 42 |
| 2.4 | SR from Insertion Devices | 43 |
| 2.4.1 | Motion of Charged Particles Inside a Planar Insertion Device | 44 |
| 2.4.2 | Resonance Wavelength | 45 |
| 2.4.3 | Radiation from Undulators and Wigglers | 46 |
| 2.4.4 | Angular Aperture of ID at Resonant Wavelength | 51 |
| 2.4.5 | Estimation of Power Distribution Radiated in a Wiggler | 52 |
| 2.4.6 | Estimation of the Power Collected by Simple Geometry Aperture | 54 |
| 2.4.7 | Method for Estimation Absorbed Power on the Complex Shapes | 54 |
| 2.5 | Software Dedicated to Evaluation of the Photon Flux and Power Distribution from the Insertion Devices | 55 |
| 2.5.1 | XOP | 56 |
| 2.5.2 | Synchrotron Radiation Workshop (SRW) | 56 |
| 2.5.3 | SPECTRA | 57 |
| 2.5.4 | SYNRAD | 58 |
| 2.5.5 | OSCARS | 59 |
| | Acknowledgements | 59 |
| | References | 60 |
| | Further Reading | 60 |
| 3 | Interaction Between SR and Vacuum Chamber Walls | 61 |
| | <i>Vincent Baglin and Oleg B. Malyshev</i> | |
| 3.1 | Photon Reflectivity | 61 |
| 3.2 | Photoelectron Production | 69 |
| 3.2.1 | Total Photoelectron Yield | 69 |
| 3.2.2 | Effect of the Photon Energy | 72 |
| 3.2.3 | Effect of the Incidence Angle | 76 |
| | References | 76 |
| 4 | Sources of Gas in an Accelerator Vacuum Chamber | 79 |
| | <i>Oleg B. Malyshev and Junichiro Kamiya</i> | |
| 4.1 | Residual Gases in Vacuum Chamber | 79 |

- 4.2 Materials Used for and in Vacuum Chambers and Built-In Elements 81
 - 4.2.1 Stainless Steel 82
 - 4.2.2 Aluminium Alloys 83
 - 4.2.3 Copper and Its Alloys 84
 - 4.2.4 Titanium and Its Alloys 85
 - 4.2.5 Ceramics 85
 - 4.2.6 Other Vacuum Materials 86
- 4.3 Thermal Outgassing 87
 - 4.3.1 Thermal Outgassing Mechanism During Pumping 88
 - 4.3.2 Equilibrium Pressure 89
 - 4.3.3 Vapour Pressure 91
 - 4.3.4 Thermal Outgassing Rate of Materials 93
 - 4.3.5 Outgassing Rate Measurements 97
 - 4.3.5.1 Throughput Method 97
 - 4.3.5.2 Conductance Modulation Method 98
 - 4.3.5.3 Two-Path Method 98
 - 4.3.5.4 Gas Accumulation Method 99
 - 4.3.6 Thermal Desorption Spectroscopy 100
- 4.4 Surface Treatments to Reduce Outgassing 102
 - 4.4.1 Cleaning 102
 - 4.4.2 Bakeout 105
 - 4.4.3 Air Bake 106
 - 4.4.4 Vacuum Firing 106
 - 4.4.5 Surface Coatings 108
 - 4.4.5.1 Coating the Surface by Thin Films of Material with Low Hydrogen Permeability and Low Outgassing 108
 - 4.4.5.2 Coating the Surface by Thin Film of Getter Materials 108
- 4.5 Electron-Stimulated Desorption 109
 - 4.5.1 ESD Definition and ESD Facilities 109
 - 4.5.2 ESD for Different Materials as a Function of Dose 112
 - 4.5.3 ESD as a Function of Amount of Desorbed Gas 113
 - 4.5.4 Effect of Pumping Duration 114
 - 4.5.5 ESD as a Function of Electron Energy 119
 - 4.5.6 Effect of Bakeout on ESD 122
 - 4.5.7 Effectiveness of Surface Polishing and Vacuum Firing on ESD 123
 - 4.5.8 A Role of Oxide Layer on Copper 125
 - 4.5.9 Effect of Surface Treatment 125
 - 4.5.10 Effect of Vacuum Chamber Temperature 125
- 4.6 Photon-Stimulated Desorption 128
 - 4.6.1 PSD Definition and PSD Facilities 128
 - 4.6.2 PSD as a Function of Dose 131
 - 4.6.3 PSD for Different Materials 131
 - 4.6.4 PSD as a Function of Amount of Desorbed Gas 135
 - 4.6.5 PSD as a Function of Critical Energy of SR 136
 - 4.6.6 Effect of Bakeout 137
 - 4.6.7 Effect of Vacuum Chamber Temperature 140

| | | |
|----------|---|------------|
| 4.6.8 | Effect of Incident Angle | 142 |
| 4.6.9 | PSD versus ESD | 144 |
| 4.6.10 | How to Use the PSD Yield Data | 145 |
| 4.6.10.1 | Scaling the Photon Dose | 145 |
| 4.6.10.2 | Synchrotron Radiation from Dipole Magnets | 145 |
| 4.6.10.3 | PSD Yield and Flux as a Function of Distance from a Dipole Magnet | 148 |
| 4.6.10.4 | PSD from a Lump SR Absorber | 151 |
| 4.6.10.5 | Combining PSD from Distributed and Lump SR Absorbers | 153 |
| 4.7 | Ion-Stimulated Desorption | 155 |
| 4.7.1 | ISD Definition and ISD Facilities | 155 |
| 4.7.2 | ISD as a Function of Dose | 156 |
| 4.7.3 | ISD Yield as a Function of Ion Energy | 158 |
| 4.7.4 | ISD Yield as a Function of Ion Mass | 159 |
| 4.7.5 | ISD for Different Materials | 160 |
| 4.7.6 | Effect of Bakeout and Argon Discharge Cleaning | 161 |
| 4.7.7 | ISD versus ESD | 161 |
| 4.7.8 | ISD Yield as a Function of Temperature | 161 |
| 4.7.9 | ISD Yields for Condensed Gases | 163 |
| | Acknowledgements | 166 |
| | References | 166 |
| 5 | Non-evaporable Getter (NEG)-Coated Vacuum Chamber | 175 |
| | <i>Oleg B. Malyshev</i> | |
| 5.1 | Two Concepts of the Ideal Vacuum Chamber | 175 |
| 5.2 | What Is NEG Coating? | 177 |
| 5.3 | Deposition Methods | 179 |
| 5.4 | NEG Film Characterisation | 181 |
| 5.5 | NEG Coating Activation Procedure | 182 |
| 5.6 | NEG Coating Pumping Properties | 188 |
| 5.6.1 | NEG Coating Pumping Optimisation at CERN | 188 |
| 5.6.2 | NEG Coating Pumping Optimisation at ASTeC | 190 |
| 5.7 | NEG Coating Lifetime | 193 |
| 5.8 | Ultimate Pressure in NEG-Coated Vacuum Chambers | 195 |
| 5.9 | NEG-Coated Vacuum Chamber Under SR | 196 |
| 5.10 | Reducing PSD/ESD from NEG Coating | 200 |
| 5.10.1 | Initial Considerations | 200 |
| 5.10.2 | ESD from Vacuum Chamber Coated with Columnar and Dense NEG Films | 201 |
| 5.10.3 | Dual Layer | 202 |
| 5.10.4 | Vacuum Firing Before NEG Deposition | 204 |
| 5.11 | ESD as a Function of Electron Energy | 204 |
| 5.12 | PEY and SEY from NEG Coating | 204 |
| 5.13 | NEG Coating Surface Resistance | 206 |
| 5.14 | NEG at Low Temperature | 207 |
| 5.15 | Main NEG Coating Benefits | 207 |

| | | |
|----------|--|------------|
| 5.16 | Use of NEG-Coated Vacuum Chambers | 208 |
| | References | 209 |
| 6 | Vacuum System Modelling | 215 |
| | <i>Oleg B. Malyshev</i> | |
| 6.1 | A Few Highlights from Vacuum Gas Dynamics | 215 |
| 6.1.1 | Gas in a Closed Volume | 216 |
| 6.1.1.1 | Gas Density and Pressure | 216 |
| 6.1.1.2 | Amount of Gas and Gas Flow | 217 |
| 6.1.2 | Total Pressure and Partial Pressure | 218 |
| 6.1.3 | Velocity of Gas Molecules | 218 |
| 6.1.4 | Gas Flow Rate Regimes | 220 |
| 6.1.5 | Pumping Characteristics | 221 |
| 6.1.6 | Vacuum System with a Pump | 223 |
| 6.1.7 | Vacuum Conductance | 223 |
| 6.1.7.1 | Orifice | 224 |
| 6.1.7.2 | Vacuum Conductance of Long Tubes | 224 |
| 6.1.7.3 | Vacuum Conductance of Short Tubes | 225 |
| 6.1.7.4 | Serial and Parallel Connections of Vacuum Tubes | 226 |
| 6.1.8 | Effective Pumping Speed | 226 |
| 6.2 | One-Dimensional Approach in Modelling Accelerator Vacuum Systems | 228 |
| 6.2.1 | A Gas Diffusion Model | 229 |
| 6.2.2 | A Section of Accelerator Vacuum Chamber in a Gas Diffusion Model | 231 |
| 6.2.3 | Boundary Conditions | 232 |
| 6.2.4 | Global and Local Coordinates for Each Element | 238 |
| 6.2.5 | Using the Results | 240 |
| 6.2.6 | A Few Practical Formulas | 241 |
| 6.2.6.1 | Gas Injection into a Tubular Vacuum Chamber | 241 |
| 6.2.6.2 | Vacuum Chamber with Known Pumping Speed at the Ends | 241 |
| 6.2.6.3 | Vacuum Chamber with Known Pressures at the Ends | 244 |
| 6.3 | Three-Dimensional Modelling: Test Particle Monte Carlo | 245 |
| 6.3.1 | Introduction | 245 |
| 6.3.2 | A Vacuum Chamber in the TPMC Model | 246 |
| 6.3.3 | TPMC Code Input | 246 |
| 6.3.4 | TPMC Code Output | 248 |
| 6.3.4.1 | Gas Flow Rate | 248 |
| 6.3.4.2 | Gas Density and Pressure | 250 |
| 6.3.4.3 | Transmission Probability and Vacuum Conductance | 250 |
| 6.3.4.4 | Pump-Effective Capture Coefficient | 251 |
| 6.3.4.5 | Effect of Temperature and Mass of Molecules | 251 |
| 6.3.5 | What Can Be Done with TPMC Results? | 251 |
| 6.3.5.1 | A Direct Model with a Defined Set of Parameters | 252 |
| 6.3.5.2 | Models with Variable Parameters | 253 |
| 6.3.6 | TPMC Result Accuracy | 256 |

| | | |
|----------|---|------------|
| 6.4 | Combining One-Dimensional and Three-Dimensional Approaches in Optimising the UHV Pumping System | 257 |
| 6.4.1 | Comparison of Two Methods | 257 |
| 6.4.2 | Combining of Two Methods | 258 |
| 6.5 | Molecular Beaming Effect | 260 |
| 6.6 | Concluding Remarks | 265 |
| 6.A | Differential Pumping | 265 |
| 6.B | Modelling a Turbo-Molecular Pump | 266 |
| | Acknowledgements | 267 |
| | References | 267 |
| 7 | Vacuum Chamber at Cryogenic Temperatures | 269 |
| | <i>Oleg Malyshev, Vincent Baglin, and Erik Wallén</i> | |
| 7.1 | Pressure and Gas Density | 269 |
| 7.2 | Equilibrium Pressure: Isotherms | 272 |
| 7.2.1 | Isotherms | 273 |
| 7.2.2 | Cryotrapping | 279 |
| 7.2.3 | Physisorption on Gas Condensates | 281 |
| 7.2.4 | Temperature Dependence of the H ₂ Isotherms | 282 |
| 7.2.5 | Choice of Operating Temperature for Cryogenic Vacuum Systems | 286 |
| 7.3 | Gas Dynamics Model of Cryogenic Vacuum Chamber Irradiated by SR | 289 |
| 7.3.1 | Infinitely Long Vacuum Chamber Solution | 291 |
| 7.3.1.1 | Vacuum Chamber Without a Beam Screen | 292 |
| 7.3.1.2 | Vacuum Chamber with Holes in the Beam Screen | 292 |
| 7.3.2 | Short Vacuum Chamber Solution | 294 |
| 7.3.2.1 | Solution for a Short Vacuum Chamber with a Given Pressure at the Ends | 296 |
| 7.3.2.2 | Solution for a Short Vacuum Chamber with a Given Pumping Speed at the Ends | 298 |
| 7.4 | Experimental Data on PSD from Cryogenic Surface | 300 |
| 7.4.1 | Experimental Facility for Studying PSD at Cryogenic Temperatures | 301 |
| 7.4.2 | Discovery of Secondary PSD | 301 |
| 7.4.3 | Calculation of the Desorption Yields from Experimental Data | 306 |
| 7.4.4 | Primary PSD Yields | 308 |
| 7.4.5 | Secondary PSD Yields | 310 |
| 7.4.6 | Photon-Induced Molecular Cracking of Cryosorbed Gas | 312 |
| 7.4.6.1 | Experimental Measurements | 312 |
| 7.4.6.2 | How to Include Cracking into the Model | 315 |
| 7.4.6.3 | Example | 316 |
| 7.4.7 | Temperature of Desorbed Gas | 318 |
| 7.5 | In-Depth Studies with COLDEX | 321 |
| 7.5.1 | COLDEX Experimental Facility | 321 |
| 7.5.2 | PSD of Cu as a Function of Temperature | 324 |
| 7.5.3 | Secondary PSD Yields | 325 |

| | | |
|----------|---|------------|
| 7.5.4 | PSD of a BS with Sawtooth for Lowering Photon Reflectivity and PEY | 326 |
| 7.5.5 | Vacuum Transient | 328 |
| 7.5.6 | Temperature Oscillations | 329 |
| 7.6 | Cryosorbers for the Beam Screen at 4.5 K | 331 |
| 7.6.1 | Carbon-Based Adsorbers | 333 |
| 7.6.1.1 | Activated Charcoal | 333 |
| 7.6.1.2 | Carbon Fibre | 334 |
| 7.6.2 | Amorphous Carbon Coating Absorption Properties | 337 |
| 7.6.3 | Metal-Based Absorbers | 338 |
| 7.6.3.1 | Aluminium-Based Absorbers | 338 |
| 7.6.3.2 | Copper-Based Absorbers | 340 |
| 7.6.3.3 | LASE for Providing Cryosorbing Surface | 341 |
| 7.6.4 | Using Cryosorbers in a Beam Chamber | 341 |
| 7.7 | Beam Screen with Distributed Cryosorber | 342 |
| 7.8 | Final Remarks | 343 |
| | References | 344 |
| 8 | Beam-Induced Electron Multipacting, Electron Cloud, and Vacuum Design | 349 |
| | <i>Vincent Baglin and Oleg B. Malyshev</i> | |
| 8.1 | BIEM and E-Cloud | 349 |
| 8.1.1 | Introduction | 349 |
| 8.1.2 | E-Cloud Models | 351 |
| 8.2 | Mitigation Techniques and Their Impact on Vacuum Design | 356 |
| 8.2.1 | Passive Methods | 357 |
| 8.2.2 | Active Methods | 363 |
| 8.2.3 | What Techniques Suit the Best | 365 |
| 8.3 | Secondary Electron Emission (Laboratory Studies) | 365 |
| 8.3.1 | SEY Measurement Method | 365 |
| 8.3.2 | SEY as a Function of the Incident Electron Energy | 367 |
| 8.3.3 | Effect of Surface Treatments by Bakeout and Photon, Electron, and Ion Bombardment | 367 |
| 8.3.4 | Effect of Surface Material | 368 |
| 8.3.5 | Effect of Surface Roughness | 369 |
| 8.3.6 | 'True' Secondary Electrons, Re-Diffused Electrons, and Reflected Electrons | 371 |
| 8.3.7 | Effect of Incidence Angle | 374 |
| 8.3.8 | Insulating Materials | 374 |
| 8.4 | How the BIEM and E-Cloud Affect Vacuum | 376 |
| 8.4.1 | Estimation of Electron Energy and Incident Electron Flux | 376 |
| 8.4.2 | Estimation of Initial ESD | 378 |
| 8.5 | BIEM and E-Cloud Observation in Machines | 379 |
| 8.5.1 | Measurements in Machines | 379 |
| 8.5.1.1 | Vacuum Pressure | 381 |
| 8.5.1.2 | Vacuum Chamber Wall Properties | 382 |
| 8.5.1.3 | Specific Tools for BIEM and Electron Cloud Observation | 386 |

| | | |
|----------|--|------------|
| 8.5.2 | Machines Operating at Cryogenic Temperature | 390 |
| 8.5.2.1 | Surface Properties at Cryogenic Temperature | 391 |
| 8.5.2.2 | Observations with Beams | 394 |
| 8.5.2.3 | The CERN Large Hadron Collider Cryogenic Vacuum System | 401 |
| 8.6 | Contribution of BIEM to Vacuum Stability | 405 |
| 8.7 | Past, Present, and Future Machines | 407 |
| | Acknowledgements | 409 |
| | References | 409 |
| 9 | Ion-Induced Pressure Instability | 421 |
| | <i>Oleg B. Malyshev and Adriana Rossi</i> | |
| 9.1 | Introduction | 421 |
| 9.2 | Theoretical | 422 |
| 9.2.1 | Basic Equations | 422 |
| 9.2.2 | Solutions for an Infinitely Long Vacuum Chamber | 425 |
| 9.2.2.1 | Room Temperature Vacuum Chamber | 425 |
| 9.2.2.2 | Cryogenic Vacuum Chamber | 426 |
| 9.2.2.3 | Summary for an Infinitely Long Vacuum Chamber | 427 |
| 9.2.3 | Short Vacuum Chamber | 428 |
| 9.2.3.1 | Solution for a Short Vacuum Chamber with a Given Gas Density at the Ends | 428 |
| 9.2.3.2 | Solution for a Short Vacuum Chamber with a Given Pumping Speed at the Ends | 431 |
| 9.2.3.3 | Solution for a Short Vacuum Chamber Without a Beam Screen Between Two Chambers With a Beam Screen | 434 |
| 9.2.3.4 | Some Remarks to Solutions for Short Tubes | 437 |
| 9.2.4 | Multi-Gas System | 437 |
| 9.2.5 | Two-Gas System | 438 |
| 9.2.5.1 | Solutions for an Infinitely Long Vacuum Chamber | 439 |
| 9.2.5.2 | Solution for a Short Vacuum Chamber in the Equilibrium State | 439 |
| 9.2.6 | Some Comments to the Analytical Solutions | 440 |
| 9.2.7 | Effect of the Ion-Stimulated Desorption on the Gas Density | 441 |
| 9.2.7.1 | Infinitely Long Vacuum Chamber (One Gas) | 441 |
| 9.2.7.2 | Vacuum Chamber with a Given Pumping Speed at the Ends (One Gas) | 441 |
| 9.2.7.3 | Two-Gas System | 443 |
| 9.2.8 | Some Numeric Examples from the LHC Design | 443 |
| 9.2.8.1 | The Critical Current for an Infinitely Long Vacuum Chamber | 444 |
| 9.2.8.2 | Short Vacuum Chambers | 445 |
| 9.2.8.3 | Effect of the Ion-Stimulated Desorption on the Gas Density | 445 |
| 9.3 | VASCO as Multi-Gas Code for Studying the Ion-Induced Pressure Instability | 447 |
| 9.3.1 | Basic Equations and Assumptions | 447 |
| 9.3.2 | Multi-Gas Model in Matrix Form and Fragmentation in Several Vacuum Chamber Elements | 448 |
| 9.3.2.1 | Boundary Conditions | 449 |
| 9.3.3 | Transformation of the Second-Order Differential Linear Equation into a System of First-Order Equations | 450 |

| | | |
|-----------|--|------------|
| 9.3.3.1 | Boundary Conditions | 451 |
| 9.3.4 | Set of Equations to be Solved | 451 |
| 9.3.5 | 'Single Gas Model' Against 'Multi-Gas Model' | 452 |
| 9.4 | Energy of Ions Hitting Vacuum Chamber | 455 |
| 9.4.1 | Ion Energy in the Vacuum Chamber Without a Magnetic Field | 455 |
| 9.4.1.1 | Circular Beams | 455 |
| 9.4.1.2 | Flat Beams | 458 |
| 9.4.2 | Ion Energy in a Vacuum Chamber with a Magnetic Field | 460 |
| 9.4.2.1 | Vacuum Chamber in a Dipole Magnetic Field | 461 |
| 9.4.2.2 | Vacuum Chamber in a Quadrupole Magnetic Field | 461 |
| 9.4.2.3 | Vacuum Chamber in a Solenoid Magnetic Field | 462 |
| 9.5 | Errors in Estimating the Critical Currents I_c | 464 |
| 9.5.1 | Beam–Gas Ionisation | 465 |
| 9.5.2 | Ion Impact Energy | 465 |
| 9.5.3 | Ion-Stimulated Desorption Yields | 465 |
| 9.5.4 | Pumping | 466 |
| 9.5.5 | Total Error in Critical Current | 466 |
| 9.6 | Summary | 467 |
| | References | 467 |
| 10 | Pressure Instabilities in Heavy Ion Accelerators | 471 |
| | <i>Markus Bender</i> | |
| 10.1 | Introduction | 471 |
| 10.2 | Pressure Instabilities | 472 |
| 10.2.1 | Model Calculations of the Dynamic Pressure and Beam Lifetime | 476 |
| 10.2.1.1 | Closed System (Vessel) | 476 |
| 10.2.1.2 | Vessel Including Collimation | 478 |
| 10.2.1.3 | Longitudinal Profile | 478 |
| 10.2.2 | Consequences | 479 |
| 10.3 | Investigations on Heavy Ion-Induced Desorption | 480 |
| 10.3.1 | Desorption Yield Measurements | 481 |
| 10.3.2 | Materials Analysis | 483 |
| 10.3.3 | Dedicated Set-ups to Measure Ion-Induced Desorption Yields | 485 |
| 10.3.4 | Results | 489 |
| 10.3.4.1 | Materials | 490 |
| 10.3.4.2 | Surface Coatings | 493 |
| 10.3.4.3 | Cleaning Methods | 494 |
| 10.3.4.4 | Energy Loss Scaling | 495 |
| 10.3.4.5 | Angle Dependence | 496 |
| 10.3.4.6 | Conditioning | 497 |
| 10.3.4.7 | Cryogenic Targets | 498 |
| 10.3.5 | Theoretic | 499 |
| 10.3.5.1 | Interaction of Ions with Matter | 499 |
| 10.3.5.2 | Inelastic Thermal Spike Model | 501 |
| 10.4 | Conclusion: Mitigation of Dynamic Vacuum Instabilities | 505 |
| | Acknowledgement | 507 |
| | References | 507 |
| | Index | 515 |

